

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Florence Eschbach et al. Art Unit: Unknown Serial No.: 10/649,355 Examiner: Unknown

Filed: August 26, 2003 Assignee: Intel Corporation

Title : MOUNTING A PELLICLE TO A FRAME

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

This filing is being made before the receipt of a first Office action on the merits. No fee is required.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

September 22, 3003

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Carroll Allman

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Respectfully submitted,

ALEX CHEN

Date: September 22, 2003

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Sheet	1	of	1
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Substitute: orm PTO-1449

(37 CFR §1.98(b))

U.S. Department of Commerce Patent and Trademark Office

Attorney's Docket No. Intel 10559-865001 / P17313

Application No. 10/649,355

## **Information Disclosure Statement by Applicant** (Use several sheets if necessary)

Applicant

Florence Eschbach et al.

Filing Date August 26, 2003 Group Art Unit

IDS filed 09/22/2003

U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD	"					
	AE						
	AF						
	AG						

Foreign Patent Documents or Published Foreign Patent Applications								
Examiner	Desig.	Document	Publication	Country or			Trans	lation
Initial	ID	Number	Date	Patent Office	Class	Subclass	Yes	No
	AH							
	AI							<b>2. 12</b>
	AJ							
	AK							
	AL							

Other Documents (include Author, Title, Date, and Place of Publication)					
Examiner	Desig.				
Initial	ID	Document			
		D.W. Van Krevelen, with the collaboration of P.J. Hoftyzer; "Properties of Polymers, Their			
	AM	Estimation and Correlation with Chemical Structure," Second, completely revised edition; 1976,			
		Elsevier Scientific Publishing Company, Amsterdam - Oxford - New York			
		Oshima et al.; Radiation Physics and Chemistry, "Chemical structure and physical properties of			
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		Reu et al.; "Mechanical analysis of hard pellicles for 157 nm lithography," to appear in the			
	AO	Proceedings of the 2001 SPIE Symposium on Optical Microlithography XIV, Vol. 4346, 2001; UW			
	AU	Computational Mechanics Center, University of Wisconsin, Madison, WI 53706; Intel Corporation,			
		Santa Clara, CA 95052			
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	AQ	Photomask Japan, 2002			

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if no next communication to applicant	t in conformance and not considered. Include copy of this form with